

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:	)	
	)	Examiner:
Yuichiro Shindo	)	
	)	Group Art Unit:
Application No.:	)	
	)	
Corresponding International Filing No.:	)	
PCT/JP2004/015777	)	
	)	
Filed: Herewith	)	
	)	
For: HIGH PURITY HAFNIUM,	)	
TARGET AND THIN FILM	)	
COMPRISING SAID HIGH	)	
PURITY HAFNIUM, AND	)	
METHOD FOR PRODUCING	)	
HIGH PURITY HAFNIUM	)	

Mail Stop PCT  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**FIRST PRELIMINARY AMENDMENT**

Sir:

**Before calculating the filing fee**, please amend the above-identified patent application as follows.

**Amendments to the Claims** are reflected in the listing of claims which begins on page two of this paper.

**Remarks** begin on page four of this paper.